

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application Serial No. .... 09/827,248  
Filing Date .... April 4, 2001  
Inventor .... David R. Hembree  
Assignee .... Micron Technology, Inc.  
Group Art Unit .... 2829  
Examiner .... V. Nguyen  
Attorney's Docket No. .... MI22-1684  
Title: Methods of Processing a Workpiece, Methods of Communicating Signals With  
Respect to a Wafer, and Methods of Communicating Signals Within a Workpiece  
Processing Apparatus

SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT


References -- See Attached Form PTO-1449

The attached form PTO-1449 is submitted in compliance with 37 CFR §1.56. No  
admission is made regarding whether all the submitted references are prior art.

Respectfully submitted,

Dated: 12/7/06

Attorney:

  
James D. Shaurette  
Reg. No. 39,833

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Sheet 1 of 1

Form PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE			ATTY. DOCKET NO. MI22-1684		SERIAL NO. 09/827,248	
LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)					APPLICANT David R. Hembree			
					FILING DATE April 4, 2001		GROUP 2829	
U.S. PATENT DOCUMENTS								
*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date if Appropriate	
	AA	6,325,536 B1	12/4/2001	Renken et al.				
	AB	6,190,040 B1	2/20/2001	Renken et al.				
	AC	6,411,116 B1	6/25/2002	DeHaven et al.				
	AD	4,284,872	8/18/1981	Graeme, Jerald G.				
	AE	4,366,379	10/26/1982	Graeme, Jerald G.				
	AF	6,293,698 B1	9/25/2001	Avis, Roger L.				
	AG	6,037,645	3/14/2000	Kreider, Kenneth G.				
	AH	4,802,099	1/31/1989	Logue, Joseph C.				
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	AJ	6,577,148 B1	6/10/2003	DeHaven et al.				
	AK							
FOREIGN PATENT DOCUMENTS								
		Document Number	Date	Country	Class	Subclass	Translation	
							Yes	No
	AL	JP406310580	11/4/1994	Japan				X
	AM	JP406310580	11/4/1994	Japan (Abstract Only)			X	
	AN							
	AO							
	AP							
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)								
	AR							
EXAMINER					DATE CONSIDERED			
<p>*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.</p>								

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